EAST Search History 10 / 50 7 52。

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Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	1	("6204544").PN.	USPAT; USOCR	OR	OFF	2006/07/10 09:04
L2	1	("6220096").PN.	USPAT; USOCR	OR	OFF	2006/07/10 09:06
L3	1	("5874575").PN.	USPAT; USOCR	OR	OFF	2006/07/10 09:06
L4	1	("5874675").PN.	USPAT; USOCR	OR	OFF	2006/07/10 09:07
L5	1	("6043524").PN.	USPAT; USOCR	OR	OFF	2006/07/10 09:08
L6	1	("5903038").PN.	USPAT; USOCR	OR	OFF	2006/07/10 09:08
L7	1	("5818093").PN.	USPAT; USOCR	OR	OFF	2006/07/10 09:09
L8	1	("5600065").PN.	USPAT; USOCR	OR	OFF	2006/07/10 09:09
L9	1	("5181156").PN.	USPAT; USOCR	OR	OFF	2006/07/10 09:11
L10	1	("5786235").PN.	USPAT; USOCR	OR	OFF	2006/07/10 09:11
L11	1	("5627397").PN.	USPAT; USOCR	OR	OFF	2006/07/10 09:12
L12	1	("5541437").PN.	USPAT; USOCR	OR	OFF	2006/07/10 09:12
L13	1	("4812888").PN.	USPAT; USOCR	OR	OFF	2006/07/10 09:12
L14	778	(438/197).CCLS.	USPAT; USOCR	OR	OFF	2006/07/10 09:13
L15	226	(438/311).CCLS.	USPAT; USOCR	OR	OFF	2006/07/10 09:13
L16	457	(438/488).CCLS.	USPAT; USOCR	OR	OFF	2006/07/10 09:13
L17	728	(438/680).CCLS.	USPAT; USOCR	OR	OFF	2006/07/10 09:13
L18	433	(438/678).CCLS.	USPAT; · USOCR	OR	OFF	2006/07/10 09:13
L19	130	(438/679).CCLS.	USPAT; USOCR	OR	OFF	2006/07/10 09:13
L20	1087	(438/706).CCLS.	USPAT; USOCR	OR	OFF	2006/07/10 09:13
L21	529	(438/712).CCLS.	USPAT; USOCR	OR	OFF	2006/07/10 09:13

## **EAST Search History**

			T		T	T
L22	1007	(438/745).CCLS.	USPAT; USOCR	OR	OFF	2006/07/10 09:13
L23	121	(438/722).CCLS.	USPAT; USOCR	OR	OFF	2006/07/10 09:14
L24	0	(438/7752).CCLS.	USPAT; USOCR	OR	OFF	2006/07/10 09:14
L25	515	(438/753).CCLS.	USPAT; USOCR	OR	OFF	2006/07/10 09:16
L26	1	("6422077").PN.	USPAT; USOCR	OR	OFF	2006/07/10 09:16
S16	0	10/507920	USPAT	OR	OFF	2006/07/06 17:39
S17	1	("4906586").PN.	USPAT; USOCR	OR	OFF	2006/07/06 17:41
S18	1	("5262000").PN.	USPAT; USOCR	OR	OFF	2006/07/06 17:42
S19	1	("6290864").PN.	USPAT; USOCR	OR	OFF	2006/07/06 17:43
S20	849	MEMS and (micro adj electro adj mechanical adj system)	USPAT	OR	OFF	2006/07/06 17:44
S21	7	S20 and (silicon and sacrificial and layer and plasma and etching and fluorine)	USPAT	OR	OFF	2006/07/06 17:51
S22	1	"6132278".PN.	USPAT; USOCR	OR	OFF	2006/07/06 17:48
S23	1	"5886265".PN.	USPAT; USOCR	OR	OFF	2006/07/06 17:49
S24	1	"5729074".PN.	USPAT; USOCR	OR	OFF	2006/07/06 17:49
S25	1	"5679895".PN.	USPAT; USOCR	OR	OFF	2006/07/06 17:50
S26	1	"5453628".PN.	USPAT; USOCR	OR	OFF	2006/07/06 17:50
S27	0	S20 and (silicon and chemistry and plasma and etching and fluorine and xenon and difluoride and bromine and trifluoride)	USPAT	OR	OFF	2006/07/06 17:53
S28	0	S20 and (silicon and chemistry and plasma and etching and fluorine and xenon and difluoride and bromine)	USPAT	OR	OFF	2006/07/06 17:53
S29	0	S20 and (silicon and chemistry and plasma and etching and fluorine and xenon and difluoride)	USPAT	OR	OFF	2006/07/06 17:53
S30	9	S20 and (silicon and chemistry and plasma and etching and fluorine)	USPAT	OR	OFF	2006/07/10 09:03

7/10/2006 9:22:35 AM Page 2